



Abstract

The invention relates to a measuring apparatus having at least one microsensor (5), in which measuring apparatus the

5 following holds true:

- the at least one microsensor has at least two chambers (20, 30) filled with a gas,
- the chambers (20, 30) are connected to one another by at least one channel (40),
- 10 - the chambers (20, 30) are, moreover, sealed off to the outside in a gastight manner, and
- a detection device (70) for detecting a gas stream flowing in the at least one channel (40) is provided, which gas stream arises on account of different pressures prevailing in the
- 15 chambers.

Furthermore, the invention relates to a method for producing a microsensor according to the invention.

20 (Figure 1)

